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Advances in Optical Thin Films VI

Michel Lequime
H. Angus Macleod
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Contents

vii	Authors
ix	Conference Committee

OPENING SESSION

- 10691 03 **Multilayer enhanced metasurfaces with high efficiency and additional functionalities (Invited Paper) [10691-2]**

DESIGN AND MODELLING

- 10691 09 **High performance atomistic simulation of thin films porosity and surface structure [10691-8]**

DEPOSITION PROCESSES

- 10691 0B **Glancing angle ion beam sputtering of optical thin films [10691-10]**
- 10691 0C **Stable, durable, low-absorbing, low-scattering MgF₂ films without heat or added fluorine [10691-11]**
- 10691 0E **Controlling mechanical, structural, and optical properties of Al₂O₃ thin films deposited by plasma-enhanced atomic layer deposition with substrate biasing [10691-13]**

DEPOSITION MONITORING AND CHARACTERIZATION I

- 10691 0F **Broad band optical monitoring of large area coatings produced using planetary rotation (Invited Paper) [10691-14]**
- 10691 0H **Time resolved detection of particle contamination during thin film deposition [10691-16]**

DEPOSITION MONITORING AND CHARACTERIZATION III

- 10691 0N **Optical characterisation of silver mirrors protected with transparent overcoats [10691-22]**
- 10691 0P **Research VIS-NIR optical constants of Si films deposited by different techniques [10691-56]**

SHORT WAVELENGTHS COATINGS

- 10691 OS **High reflectance broadband thin films used in x-ray telescopes** [10691-26]
- 10691 OT **Enhanced far-UV reflectance of Al mirrors protected with hot-deposited MgF₂** [10691-27]
- 10691 OU **Aperiodic x-ray multilayer interference coatings with high reflectance and large field of view** [10691-28]

POST-DEADLINE SESSION

- 10691 0W **Transport mirror laser damage mitigation technologies on the National Ignition Facility** [10691-79]
- 10691 0X **Effects of adhesion layer composition on the environmental durability of protected silver mirrors** [10691-80]

MATERIALS

- 10691 0Z **Colour neutral antireflection coatings for strongly curved lenses using organic nanostructures as low-n template** [10691-31]
- 10691 10 **Reproducibility and stability of nanoporous SiO₂ thin film coatings** [10691-33]
- 10691 12 **Investigation of Sc₂O₃ for high laser durability ultraviolet coating applications** [10691-50]

COATINGS AND LASERS

- 10691 15 **Nonlinear optical thin films for super-resolved direct laser writing** [10691-37]

FILTERS AND MANUFACTURING I

- 10691 18 **Development of a broadband dielectric beam splitter coating with reduced spectral wavefront error** [10691-40]
- 10691 19 **Design and fabrication of broadband polarising beam splitter cubes** [10691-41]

10691 1A **Manufacturing of high performance VIS-NIR beam splitters by plasma assisted thin film deposition technologies** [10691-42]

10691 1B **Comparison of ALD and IBS HfO₂/Al₂O₃ anti-reflection coatings for the harmonics of the Nd: YAG laser** [10691-43]

FILTERS AND MANUFACTURING II

10691 1C **Fabrication of a glancing-angle-deposited distributed polarization rotator for ultraviolet applications** [10691-44]

10691 1E **Si/SiO₂-based filter coatings for astronomical applications in the IR spectral range** [10691-46]

10691 1F **Optimal design and fabrication of multilayer antireflection coating for III-V quadruple-junction solar cells** [10691-47]

10691 1H **Improvement of the IR detectors by plasmon resonance using transparent nanoparticles obtained by the colloid dispersion synthesis: overview** [10691-49]

POSTER SESSION

10691 1K **Design and fabrication of narrowband 121.6nm minus filters** [10691-52]

10691 1P **Improvement to the LIDT of high-reflection coatings by planarization of nodular defects** [10691-58]

10691 1Q **Design and fabrication of broadband infrared durable antireflection coatings on Ge** [10691-60]

10691 1R **Design of reflective filter based on metal-dielectric thin films for radiation wavelength of carbon dioxide** [10691-61]

10691 1S **Ultra-broadband perfect absorber based on successive nano-Cr-film** [10691-62]

10691 1T **Hyperbolic metamaterials based on metal-dielectric thin layers** [10691-63]

10691 1U **Analyses of tabulated optical constants for thin films in the EUV range and application to solar physics multilayer coatings** [10691-64]

10691 1V **Enhancement of optical resistance in high reflectivity mirrors using sculptured thin films** [10691-65]

10691 1W **Influence of substrate cleaning on the laser resistance of antireflective coatings** [10691-66]

10691 1Y **Optimization of thermal evaporation for continuous silver films and their application for non-polarizing optical components** [10691-68]

- 10691 1Z **Modeling and manufacture of an interference filter with a defective layer for narrow spectral selection** [10691-69]
- 10691 20 **Anisotropic coatings for normal incidence applications** [10691-70]
- 10691 21 **Fabrication of phase diffractive optical elements by direct laser writing process in aluminum thin films** [10691-71]
- 10691 23 **Oxygen plasma etching of YAG crystals** [10691-73]
- 10691 24 **Design, fabrication, and characterisation of wire grid polarizers for the deep UV spectral range** [10691-74]
- 10691 27 **Fluorescence studies on optical coatings** [10691-77]
- 10691 28 **Organic framework engineering in mesoporous Nb₂O₅ thin films used as an active medium for organic vapors sensing** [10691-78]

Authors

Numbers in the index correspond to the last two digits of the seven-digit citation identifier (CID) article numbering system used in Proceedings of SPIE. The first five digits reflect the volume number. Base 36 numbering is employed for the last two digits and indicates the order of articles within the volume. Numbers start with 00, 01, 02, 03, 04, 05, 06, 07, 08, 09, 0A, 0B...0Z, followed by 10-1Z, 20-2Z, etc.

- Abdeddaim, Redha, 1T
Abromavičius, Giedrius, 23
Ahrens, Jennifer, 18
Akhouayri, H., 15
Alameda, Jennifer, 0U
Alig, Thimotheus, 27
Andreae, Lars, 19
Auchère, Frédéric, 1U
Babeva, T., 28
Bächli, Andreas, 1W
Balasa, Istvan, 0H
Baranov, Aleksandr N., 1Q
Barrie, James D., 0X
Bass, Issac L., 0W
Beladiya, V., 0E
Belosludtsev, Alexandr, 1Y, 23
Bischoff, Martin, 19
Borrise, Xavier, 24
Botha, Roelene, 1W
Bourgade, A., 15
Breese, Mark B. H., 24
Britze, Chris, 18
Bruns, Stefan, 18
Burcklen, Catherine, 0U
Buzelis, Rytis, 1V, 20
Chavero-Royán, José, 0T
Chen, Bo, 1K
Cheng, Xinbin, 03, 1F, 1P, 1S
Christova, D., 28
Chu, Chung-Tse, 0X
Citra Asmara, Teguh, 24
Cross, David A., 0W
Cucinelli, Marco, 1W
Davis, James A., 0W
De Rossi, Sébastien, 1U
Delmotte, Franck, 1U
Dong, Siyu, 1F
Du, Jing, 12
Ebert, Wolfgang, 0B
Enoch, Stefan, 1T
Espinosa-Yáñez, Lucía, 0T
Faraz, T., 0E
Fedoseev, Viktor, 0F
Folger, Kelsey A., 0X
Follert, R., 1E
Fomchenkov, Sergey A., 1Z, 21
Foster, J., 1C
Gäbler, D., 1E
Georgiev, R., 28
Georgieva, B., 28
Ghazaryan, L., 10
Gischkat, Thomas, 1W
Gricius, Karolis, 20
Grigoriev, F. V., 09
Grinevičiūtė, Lina, 1V, 20
Gubanova, Lyudmila A., 1Q
Guerrero, Albert, 24
Günther, Sven, 1W
Gutiérrez-Luna, Nuria, 0T
Hart, Gary A., 12
Hau-Riege, Stefan P., 0U
He, Tao, 03, 1P
Heussler, Sascha Pierre, 24
Hoffman, B. N., 1C
Honrado-Benítez, Carlos, 0T
Huang, Qiushi, 0S
Huo, Tonglin, 1K
Iliopoulos, K., 15
Jakobs, Stefan, 1A
Jensen, Lars, 0H, 1B, 27
Ji, Yiqin, 0P, 1R
Jiang, Yugang, 0P
Jiao, Hongfei, 03, 1F, 1P, 1S
Jurkšaitis, Povilas, 1Y
Kaiser, N., 0N
Kessels, W. M. M., 0E
Kessler, T. J., 1C
Kičas, Simonas, 1V, 1Y
Kirschner, Volker, 18
Knopf, H., 0Z
Kozlov, Ivan, 0F
Kricheldorf, Hans-Ulrich, 0H
Kyžas, Naglis, 23
Lappschies, Marc, 1A
Larraquert, Juan I., 0T
Lemarchand, Fabien, 1T
Leng, Jian, 0P
Li, Jing, 1F
Lingley, Zachary R., 0X
Liu, Dandan, 0P, 1R
Liu, F., 15
Liu, H., 1B
Liu, Huasong, 0P, 1R
Liu, Xiaoli, 1R
Liu, Yang, 1K
Lumeau, Julien, 15, 1T
Ma, Bin, 1P
Ma, P., 1B

- MacGowan, Brian J., 0W
 MacNally, S., 1C
 Mädebach, H., 1B
 Mann, Klaus, 18
 Mas, Roser, 24
 Melchakov, Evgeni, 1U
 Mende, Mathias, 0B
 Mikheeva, Elena, 1T
 Miller, Philip E., 0W
 Mirkarimi, Paul, 0U
 Moisset, C., 15
 Moreau, Antonin, 1T
 Munzert, P., 0Z
 Natoli, J.-Y., 15
 Negres, Raluca A., 0W
 Ni, Hangjian, 0S
 Niu, Xinshang, 1S
 Novikov, Pavel, 0F
 Oliva, E., 1E
 Oliver, J. B., 1C
 Ong Bin, Leong, 24
 Oudard, Jean Francois, 12
 Palmisano, M., 0N
 Papernov, S., 1C
 Pardini, Tom, 0U
 Pavlyshin, Dmitry, 0F
 Perea-Abarca, Belén, 0T
 Perrin, C., 15
 Piegar, A., 0N
 Porfirev, Alexey P., 1Z, 21
 Protopapa, M. L., 0N
 Qiu, S. Roger, 0W
 Ramalis, Lukas, 20
 Rebellato, Jennifer, 1U
 Rickett, F., 0Z
 Ristau, Detlev, 0H, 1B, 27
 Robinson, Jeff, 0U
 Rodríguez-de Marcos, Luis V., 0T, 24
 Rüsseler, Anna Karoline, 0H
 Rusydi, Andriyo, 24
 Savkina, Rada K., 1H
 Schäfer, Bernd, 18
 Schlegel, R., 1E
 Schulz, U., 0Z
 Schürmann, M., 0N, 1E
 Schwinde, S., 0N, 1E
 Seemann, U., 1E
 Shakouri, R., 0C
 Sitzman, Scott D., 0X
 Smirnov, Alex B., 1H
 Smith, C., 1C
 Sommer, Stanley, 0W
 Soufli, Regina, 0U, 1U
 Spaulding, J., 1C
 Spiller, Eberhard, 0U
 Stevanovic, Igor, 1W
 Stoltz, Christopher J., 0W
 Stuart, Sean C., 0X
 Sulimov, V. B., 09
 Sun, Peng, 1R
 Syčhková, A., 0N
 Szeghalmi, A., 0E, 10
 Tikhonravov, Alexander, 09, 0F
 Tolenis, Tomas, 1V, 20
 Tünnermann, A., 0E
 Udovitska, Ruslana S., 1H
 Valavičius, Audrius, 1Y
 Vergöhl, Michael, 0H, 18
 Voznyuk, Ivan, 1T
 Walton, Chris, 0U
 Wang, Jue, 12
 Wang, Xiaodong, 1K
 Wang, Zhanshan, 03, 0S, 1F, 1P, 1S
 Weber, Thomas, 1A
 Wegner, Paul J., 0W
 Weinert, Udo, 19
 Wenger, Jérôme, 1T
 Whitman, Pamela K., 0W
 Widmayer, Clay C., 0W
 Willey, Ronald R., 0C
 Xie, Lingyun, 1P
 Xing, Yuzhe, 0P
 Yang, Xiao, 1R
 Yang, Yang, 0S
 Zhang, Jinlong, 03, 1F, 1P, 1S
 Zhang, Xuemin, 1S
 Zhang, Xueyan, 1U
 Zhang, Zhong, 0S
 Zhao, Yiming, 1F
 Zhou, Hongjun, 1K
 Zhou, Zhou, 03
 Zhuang, Kewen, 0P
 Zhupanov, Valery, 0F

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- 5 Deposition Monitoring and Characterization II
Anna Sychkova, ENEA (Italy)
- 6 Deposition Monitoring and Characterization III
Michel Lequime, Institut Fresnel (France)
- 7 Short Wavelengths Coatings
Norbert Kaiser, Fraunhofer-Institut für Angewandte Optik und Feinmechanik (Germany)
- 8 Post-deadline Session
Detlev Ristau, Laser Zentrum Hannover e.V. (Germany)
- 9 Materials
Adriana Szeghalmi, Fraunhofer-Institut für Angewandte Optik und Feinmechanik (Germany)
- 10 Coatings and Lasers
Christopher J. Stoltz, Lawrence Livermore National Laboratory (United States)
- 11 Filters and Manufacturing I
Michel Lequime, Institut Fresnel (France)
- 12 Filters and Manufacturing II
Marco Jupé, Laser Zentrum Hannover e.V. (Germany)